# DST3

# **Triplet Target Sputtering System**

A versatile, high vacuum sputtering solution for thin film and SEM applications



# **DST3** features

- ☐ Triplet sputter head
- 🛮 Large format chamber
- O High resolution turbomolecular pumping
- O Fully automated colorful touch-screen control
- Able to plot sputtering parameters graphs
- ☐ Including USB port for graph and data extraction and software updates
- O Thickness monitor system for thickness measuring during coating process



Nano Structured Coatings Co.

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# **Desk Sputter Coater DST3**

The DST3 is available in two options:

### **DST3 S - Linear (or Straight) cathodes**

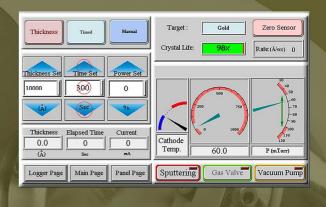
The DST3 is a coating system with a large chamber and turbo molecular-pump. It is suitable to sputter large single sample with specimen diameter up to 20 cm. Smaller multiple specimens can be sputtered over a similar diameter.

To ensure an even deposition ratio over a large diameter, the DST3 is equipped with three sputtering heads. The system is capable to sputter both oxidizing metals and non-oxidizing noble metals.

### **DST3 A-30 degree angled cathodes**

DST3A model is a desk sputter coater equipped with turbo molecular pump. It can sputter metals, semiconductors and dielectric targets. It is also capable to co-sputter two or three cathodes simultaneously by using three angular cathodes via a common focal point.

#### STANDARD FEATURES ☐ Two-stage, direct drive 170 lpm, rotary vane pump ☐ High vacuum turbo pump 60 l/s ☐ 3 water cooled 2" cathodes ☐ Deposition continuously without need to rest □ 300 mm OD x 180 mm Pyrex cylinder chamber $\square$ 0-100 mA DC power supply □ 7" touch screen control panel; includes features such as a log of the last 200 coatings carried out ☐ Ultimate Vacuum: Less than 4×10-5 millitorr ☐ Dimensions: 50 Cm H x 60 Cm W x 47 Cm D ☐ Utilities: 220V-50Hz - 6A $\square$ Gas: Argon – 99.999% (regulated to 2 – 5 psig); recommended but not required. ☐ Manual or automatic Timed and Thickness sputtering. ☐ Control the rate of sputtering for any cathode independently, to achieve finer grain structure ☐ High precision quartz crystal thickness monitor. ☐ Protection of samples against heating during sputtering process ☐ System automatically vents when turned off. $\square$ Automatically controlled the power of sputtering independent of pressure ☐ Automatically controlled the temperature of cathodes in order to protect the life time of the magnets ☐ Equipped with rotary sample holder with ability of tilting in direction of cathode ☐ Data is rapidly entered using fully automatic touch screen control ☐ Precision Mass Flow meter (MFC) in order to fine control of the vacuum pressure ☐ Drawing the pressure, thickness and current curves. $\Box$ Transfer the curves and sputtering process data by **USB** port to PC ☐ Shipping Weight: ~ 27 Kg (without vacuum pump). ~ 43 Kg with pump







#### **Options**

□ 300 W R	F power suppl	ly and	match	hing box	K
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- ☐ 500 mA DC power supply
- ☐ Nitrogen venting gas
- ☐ Substrate bias voltage
- ☐ Rotatable sample stage
- $\square$  Angled sample stage





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